LISTING OF THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

1.   **(Currently Amended)**   A substrate processing apparatus, comprising:

a first processing chamber capable of being isolated from an external atmosphere, said first processing chamber including a liquid chemical processing part for performing liquid chemical process on substrates, and the atmosphere within said first processing chamber being continuously replaced by an inert gas;

a second processing chamber capable of being isolated from an external atmosphere, said second processing chamber including a pure water processing part for performing pure water process on substrates, and a dry processing part for performing dry process on substrates, and the atmosphere within said second processing chamber being continuously replaced by an inert gas;

a first opening provided to an upper portion of said first processing chamber, said first opening allowing substrates to pass therethrough;

a first shutter member for exposing and blocking said first opening;

a second opening provided to an upper portion of said second processing chamber, said second opening allowing substrates to pass therethrough;

a second shutter member for exposing and blocking said second opening;

a third opening provided between said first and second processing chambers, said third opening allowing substrates to pass therethrough;

a third shutter member for exposing and blocking said third opening, said third shutter member being effective in a closed state thereof to isolate the atmosphere within said first processing chamber from the atmosphere within said second processing chamber;

a first transport mechanism for transporting substrates, said first transport mechanism being movable between a position above said first processing chamber and a position above said second processing chamber;

a second transport mechanism for carrying substrates between said first and second processing chambers through said third opening;

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